BIRLA INSTITUTE OF TECHNOLOGY AND SCIENCE PILANI, Hyderabad Campus

FIRST SEMESTER 2023-2024 Course Handout (Part II)

In addition to Part I (general Handout for all courses appended to the Time Table), this portion gives further specific details regarding the course.

Course No. : PHY F417

Course Title : Experimental Methods of Physics

Instructor : Souri Banerjee

Course Description: Optical and dielectric measurements, computer interfacing, Vacuum Techniques, Cryogenics, synthesis and properties of materials, structural characterization with modern experimental techniques including microscopy and spectroscopy.

Scope & Objective: The course will cover modern techniques used in experimental physics research laboratories and in industries working in related fields.

Text Book: No single textbook exists.

Reference books:

- 1. L.L. Marton, *Methods of Experimental Physics*, Volumes 1-26 (Academic Press, 1952, New York)
- 2. The Science & Engineering of Microelectronics Fabrication, S. A Campbell, Oxford Univ Press
- 3. R.C. Richardson and E. N. Smith, *Experimental Techniques in Condensed Matter Physics at Low Temperatures* (Addison-Wesley, 198, Redwood City)
- 4. G.K. White, *Experimental Techniques in Low Temperature Physics*, 3rd edition (Clarendon, 1987, Oxford)
- 5. L.G. Carpenter, Vacuum Technology, 2nd edition (Adam Hilger, 1983, Bristol)
- 6. J.F. O' Hanlan, A User's Guide to Vacuum Technology, 2^{nd} edition (Wiley, 1989, New York)
- 7. Helfrick and Cooper, *Modern electronic instrumentation and measurement techniques* (Prentice Hall)

Course Plan:

| Lecture No. | Learning Objectives | Topics to be covered | Reference |
|----------------|---|---|---|
| 1-4 | The relevance of course | Important points that the course will cover | (Chap/Sec) Ref |
| 5-15 | Methods to dope materials and test the doping level, Oxidation | Diffusion & ion implantation. Diffused profile analysis. Oxide thickness measurements | Lecture notes + relevant portions from reference books. |
| 16-28 | Lithography | Experimental methods involving various kinds of lithography | Do |
| 29-35 | Electron Microscopy and Spectroscopic Techniques | SEM, TEM, SPM | Do |

| 36-42 | Vacuum deposition | Thin films, CVD etc | |
|-------|-------------------|---------------------|----|
| | | | Do |

Evaluation Scheme:

| EC | Evaluation Scheme | Duration | Weightage | Date & Time | Nature of |
|-----|-------------------|----------|-----------|-----------------------|-----------|
| No. | | | (%) | | Component |
| 1. | Midsem | 90 mins. | 30 | 07/10 - 4.00 - 5.30PM | Open Book |
| 2. | Lab Project | | 20 | | |
| 3. | Research Seminar | | 10 | | |
| 4. | Comprehensive | 3 hrs. | 40 | 05/12 AN | Open Book |
| | Examination | | | | |

Notices: Notices for the course will be displayed on **Physics** notice board. **Make-up Policy:** Make up will be given strictly to **genuine cases only** i.e. **(i)** Sickness leading to hospitalization, **(ii)** Out of station with prior intimation &permission.

Academic Honesty and Integrity Policy: Academic honesty and integrity are to be maintained by all the students throughout the semester and no type of academic dishonesty is acceptable.

Instructor-in-Charge PHY F417